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Advanced Laser Processing and Manufacturing VIII

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Editors

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Contents

v	Symposium Committees
ix	Conference Committee

WELDING AND RELATED PHENOMENA

- 13234 03 **Oscillating laser hot-wire welding morphology quality control of aluminum alloys** [13234-2]
- 13234 04 **Study on oscillating laser welding of plastic and metal dissimilar materials** [13234-3]

LASER APPLICATIONS IN LITHOGRAPHY

- 13234 07 **Laser self-reference technique for high-precision lithographic alignment** [13234-7]
- 13234 08 **Interference laser lithography for sub-wavelength gratings in visible light** [13234-8]
- 13234 09 **Fabrication of optical mosaic gratings** [13234-9]
- 13234 0A **Free-space and solid-matrix-media diffraction neural network masks made by two-photon lithography** [13234-10]

FEMTO/PICO-SECOND LASER PROCESSING

- 13234 0B **Micropore processing technology and quality evaluation of HTCC based on UV picosecond laser** [13234-11]
- 13234 0C **Ring-shaped random structures inscription in multimode fibers assisted by a spatial light modulator** [13234-12]

ADDITIVE MANUFACTURING

- 13234 0F **The microstructure and arc-ablation property of Cu-Ta alloy prepared by laser directed energy deposition** [13234-16]
- 13234 0G **An ultrasensitive 3D-printed nano mechanics sensor** [13234-17]

LASER SURFACE MODIFICATION

- 13234 OI **Laser hybrid electrochemical surface modification of titanium alloys (Invited Paper)**
[13234-19]
- 13234 OJ **Investigation on laser annealing mechanism of fused silica optics polished by CO₂ lasers based on fictive temperature distribution** [13234-20]
- 13234 OK **Femtosecond laser processing of superhydrophobic microstructures on the surface of AH36 steel plate** [13234-22]
- 13234 OL **Laser ablation of alumina structural ceramics using fiber lasers and simulation analysis**
[13234-23]

POSTER SESSION

- 13234 OM **Effect of laser power and focal spot size on the performance of LPBF systems** [13234-5]
- 13234 OO **Multispot laser peening using phase modulated laser beam** [13234-24]
- 13234 OP **Laser peening in a high-vacuum environment** [13234-25]
- 13234 OQ **Morphology and free-electron density evolution in ablation of fused silica with mJ-level femtosecond pulsed laser** [13234-26]
- 13234 OR **Laser-induced fabrication of polymer templates for directed assembly of nanostructures**
[13234-27]
- 13234 OS **Optimizing 3D ceramic printing: a mixed powder approach to enhance surface quality and forming precision** [13234-28]
- 13234 OT **Research on the thermo-mechanical coupled numerical simulation of laser cladding 316L+H13/20%WC composite coatings on H13 steel surface** [13234-29]
- 13234 OU **Experimental study on the laser cladding of H13+H13/20%WC composite coating on H13 steel surface** [13234-30]
- 13234 OV **Superwetting surface processed by a femtosecond laser for spontaneous directional transport of fluid** [13234-31]
- 13234 OW **New technological solutions for the manufacturing and sharpening of three-flute drills**
[13234-32]
- 13234 OX **Thermal resistance investigate of copper-copper interface based on femtosecond laser periodic microstructure** [13234-33]
- 13234 OY **Laser cladding of wear-resistant coatings based on chromium and molybdenum carbides**
[13234-34]

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